

PATENT  
Atty. Dkt. No. APPM/001570.C2/DSM/HDP/JP  
Serial No.: 08/912,112

**IN THE CLAIMS:**

Please amend the claims as follows:

1-14. (Canceled)

15. (Currently Amended) A ~~An electrically symmetric~~ processing enclosure, comprising:

a chamber body defining an annular interior processing region, the annular processing region tapering towards a lower end;

an exhaust passage concentrically positioned in the lower end of the chamber body;

a cantilever mounted annular substrate support member affixed to the chamber body at a position above and concentric to the exhaust passage; and

a lid member disposed over an annular open top portion of the chamber body, the lid member having an energy transmitting dome made of a dielectric material, an energy delivery assembly, and a temperature control assembly mounted thereto.

16. (Currently Amended) The processing enclosure of claim 15, wherein the cantilevered mounted substrate support member comprises:

a base member having a flange extending therefrom, the flange being configured to attach to an interior surface of the chamber body and form a smooth surface therewith;

at least one cantilevered arm portion extending radially inward from the base member; and

a substrate receiving member mounted to a distal end of the at least one cantilevered arm portion, the substrate receiving member having an annular outer surface.

17. (Previously Presented) The processing enclosure of claim 16, wherein the annular outer surface defines an annular passage between the outer surface and the annular interior processing region.

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